- 2 second deflector generate deflection fields of different strengths.
- 1 10. (New) An electron optical column as in claim 1, wherein said scanning deflector
- 2 comprises octupole deflectors.
- 1 11. (New) An electron optics assembly as in claim 1, wherein said scanning deflector
- 2 comprises titanium alloy elements brazed to a ceramic substrate.
- 1 12. (New) An electron optics assembly for a multi-column electron optical system
- 2 comprising:
- means for generating a multiplicity of electron beams;
- 4 a multiplicity of focus lenses, configured such that there is a corresponding focus lens for
- 5 each column; and
- a multiplicity of scanning deflectors situated above said focus lenses, such that there is a
- 7 corresponding scanning deflector for each column, each said scanning deflector comprising a
- 8 first deflector and a second deflector configured to provide telecentric scanning of said electron
- 9 beams on a specimen substrate positioned below said focus lenses.
- 1 13. (New) An electron optics assembly as in claim 6, wherein said scanning deflectors are
- 2 electrostatic deflectors.
- 1 14. (New) An electron optics assembly as in claim 7, wherein said first deflectors and said
- 2 second deflectors generate electric fields of opposite polarities.
- 1 15. (New) An electron optical column as in claim 6, wherein said first deflectors and said
- 2 second deflectors generate deflection fields of different strengths.
- 1 16. (New) An electron optics assembly as in claim 6, wherein said scanning deflectors are

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2 octupole deflectors.

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1 17. (New) An electron optics assembly as in claim 6, wherein each of said scanning

2 deflectors comprises titanium alloy elements brazed to a ceramic substrate.

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